

# ICMAP 2018

The 7th International Conference on Microelectronics and Plasma Technology

July 24–28, 2018 / Songdo ConvensiA, Incheon, Korea

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## **Prof. Yeon Ho Im**

Chonbuk National University, Republic of Korea

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Yeon Ho Im, Ph.D. has been a professor in School of Semiconductor and Chemical Engineering at Chonbuk National University since 2005. He has developed a commercialized software (K-SPEED) for 3D feature profile simulation of plasma etching and deposition processes. Prior to joining Chonbuk National University, Im was a senior engineer to develop contact etch processes of DRAM and Flash memory in the Memory Division at SAMSUNG. Im received a Ph.D. degree in plasma etch field from Chonbuk National University, Jeonju, Korea. He joined the Center for Gigascale Integration at Rensselaer Polytechnic Institute (USA) as a postdoctoral fellow to develop three dimensional feature scale simulator (PLENTE and EVOLVE) from 2002 to 2003. In 2014, he worked as a visiting scholar at Prof. Graves lab, UC Berkeley (USA) to perform molecular dynamics simulation for plasma etching process.